

A MIXING SYSTEM

Abstract of the Disclosure

5 A mixing system 100 that includes the pressure regulator (140), the
mixing chamber (145), the controller (147) and the detector (150) which
form a control loop to provide a mixture of de-ionised (DI) water and carbon
dioxide (CO₂) gas having a desired resistivity value for a semiconductor
processing system. When the value of the resistivity of the mixture is not
10 controlled the shut-off valve (155) and the drain valve (160) are activated to
divert the mixture away from the semiconductor processing system.

(FIG. 1 accompanies this abstract)